



PATENT  
97-CT-174

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
RAFFAELE ZAMBRANO )  
Serial No.: 09/191,743 )  
Filed: November 13, 1998 )  
For: IN-SITU DEPOSITION AND )  
DOPING PROCESS FOR POLY- )  
CRYSTALLINE SILICON LAYERS )  
AND THE RESULTING DEVICE )  
\_\_\_\_\_ )

Group Art Unit: 2823

Examiner: M. Estrada

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AMENDMENT

Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated December 28, 2001, the due date for response to which has been extended to June 28, 2002 by the enclosed petition for extension of time, in connection with the above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents,

Washington, D.C. 20231, on 6/28/02.  
Date of Deposit

Stephen Bongini  
Applicant, Assignee, or Representative

Signature

6/28/02  
Dated

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